

Fig. 1A

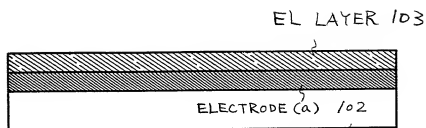


Fig. 1B: PLASMA PROCESSING STEP

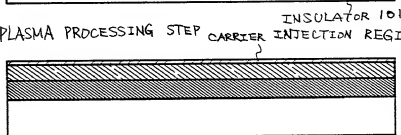


Fig. 1C

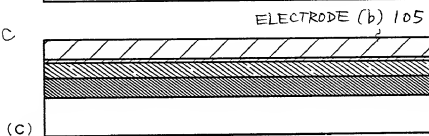


Fig. 1D

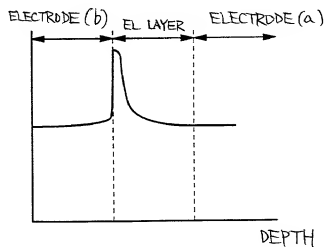
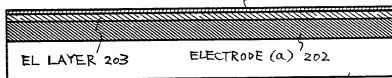


Fig. 2A PLASMA PROCESSING STEP CARRIER BLOCKING REGION (a) 204



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Fig. 2B PLASMA PROCESSING STEP CARRIER BLOCKING REGION (b) 205

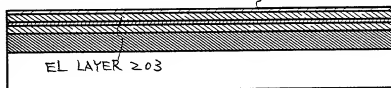


Fig. 2C

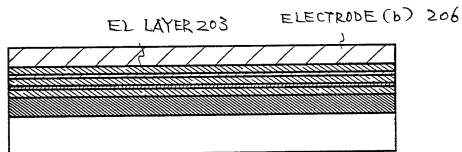


Fig. 3A

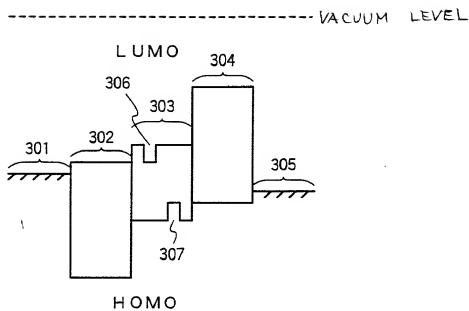


Fig. 3B

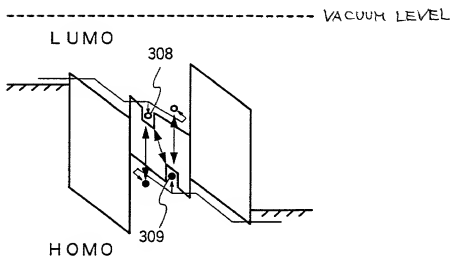


Fig. 4A

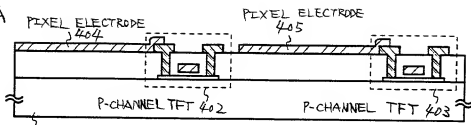


Fig. 4B

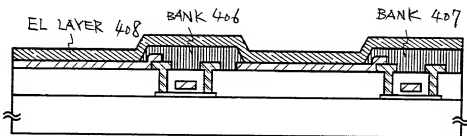


Fig. 4C

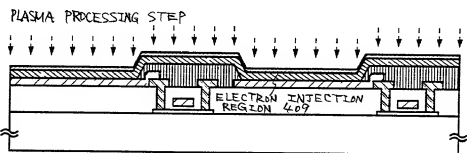


Fig. 4D

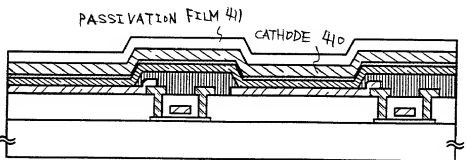


Fig. 5A

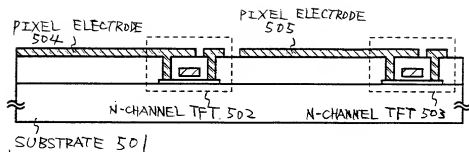


Fig. 5B

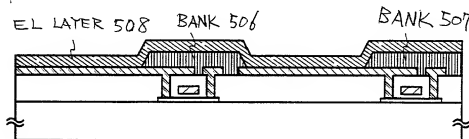


Fig. 5C PLASMA PROCESSING STEP

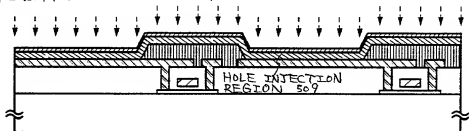


Fig. 5D

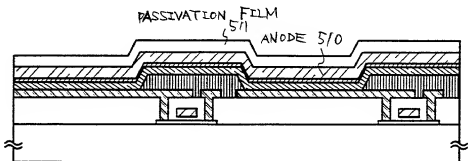


Fig. 6A

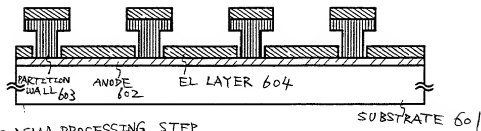


Fig. 6B PLASMA PROCESSING STEP

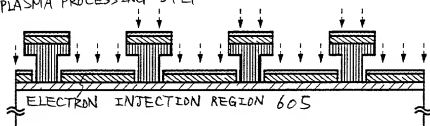


Fig. 6C PASSIVATION FILM 607

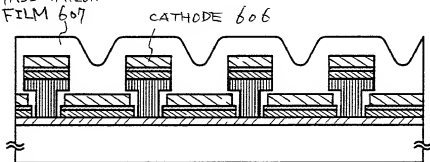


Fig. 7A

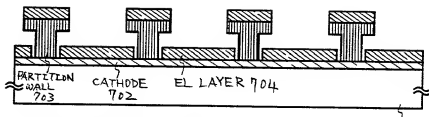


Fig. 7B PLASMA PROCESSING STEP

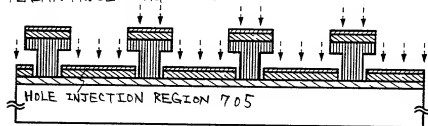
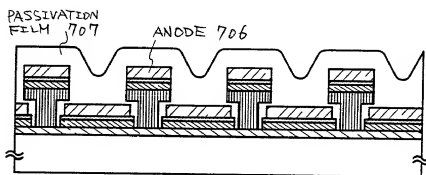


Fig. 7C



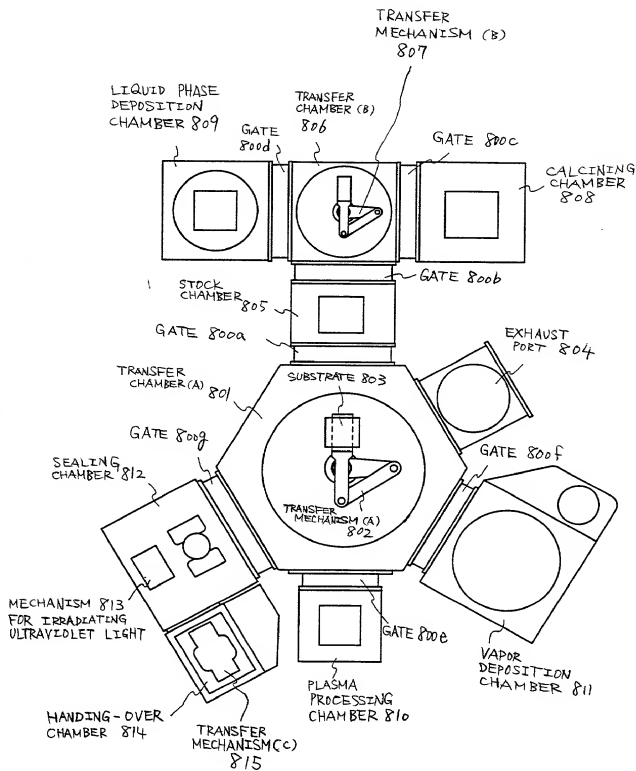


Fig. 8



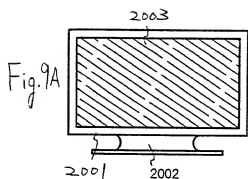


Fig. 9A

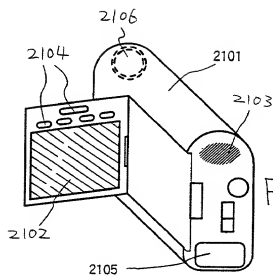


Fig. 9B

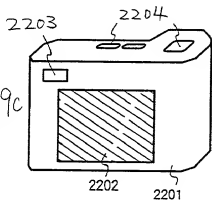


Fig. 9C

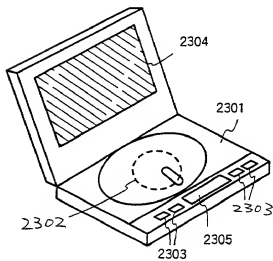


Fig. 9D

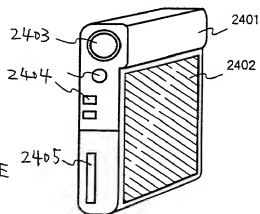


Fig. 9E

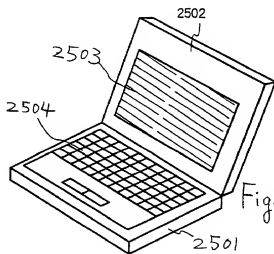


Fig. 9F

